Page 2

01/21/2003 15:44 FAX 61230512

Amendment and Response Serial No.: 09/942,200

Confirmation No.: 8194 Filed: 29 August 2001

For: DIFFUSION BARRIER LAYERS AND METHODS OF FORMING SAME

In the Claims

Please amend claims 23, 27, and 31-32. The amended claims are provided below in clean form. Per 37 C.F.R. § 1.121, amended claims are also shown in Appendix A with notations to indicate changes made (for convenience, all pending claims are provided in Appendix A).



23. (Once Amended) A semiconductor device structure, the structure comprising:

a substrate assembly including a surface; and

a chemical vapor deposited barrier layer over at least a portion of the surface, wherein the barrier layer is formed of a platinum(x):ruthenium(1-x) alloy, where x is in the range of about 0.60 to about 0.995, and further wherein the barrier layer is substantially free of carbon.



27. (Once Amended) A capacitor structure comprising:

- a first electrode;
- a dielectric material on at least a portion of the first electrode; and
- a second electrode on the dielectric material, wherein at least one of the first electrode and second electrode comprises a chemical vapor deposited barrier layer of platinum(x):ruthenium(1-x) alloy, and further wherein the barrier layer is substantially free of carbon.



- 31. (Once Amended) The structure of claim 30, wherein the one or more additional conductive layers are formed from materials selected from the group of metals and metal alloys; metal and metal alloy oxides; metal nitrides; and metal silicides.
- 32. (Once Amended) A memory cell structure comprising: a substrate assembly including at least one active device; and

01/21/2003 15:44 FAX 6123051

Amendment and Response

Serial No.: 09/942,200 Confirmation No.: 8194 Filed: 29 August 2001

Page 3

For: DIFFUSION BARRIER LAYERS AND METHODS OF FORMING SAME

a capacitor formed relative to the at least one active device, the capacitor comprising at least one electrode including a chemical vapor deposited barrier layer formed of platinum(x):ruthenium(1-x) alloy, wherein the barrier layer is substantially free of carbon.